

## **LISTING OF THE CLAIMS**

This listing of claims will replace all prior versions, and listings, of claims in the application:

**1. - 8. (Canceled)**

**9. (Currently Amended)** A substrate treating apparatus comprising:  
a support means including a chuck rotatable by a motor for supporting and spinning a substrate in a horizontal plane;  
a cleaning solution supply means including [[having]] a nozzle for supplying a cleaning solution having ozone dissolved therein to an upper surface of said substrate;  
an ultraviolet emitter means including UV lamps and a reflector for emitting ultraviolet light to said substrate; said ultraviolet emitting means emitting ultraviolet light to said substrate from an irradiating position above said support means; and  
wherein, during a cleaning process in which said cleaning solution is supplied from said cleaning solution supply means to said substrate supported and spun by said support means, said ultraviolet emitting means emits a controller for rotating said support means supporting said substrate, supplying said cleaning solution from said nozzle of said cleaning solution supply means to said substrate supported and spun, and, during this cleaning process, supplying power to said UV lamps to emit ultraviolet light to said cleaning solution supplied to said substrate and forming a puddle on an upper surface of said substrate.

**10. (Previously Presented)** An apparatus as defined in claim 9, wherein the ultraviolet light has a wavelength in a range of 242.4 to 300nm.

**11. (Previously Presented)** An apparatus as defined in claim 9, including base adding means for adding a base to the cleaning solution.

**12. (Previously Presented)** An apparatus as defined in claim 10, including base adding means for adding a base to the cleaning solution.

**13. - 24. (Canceled)**

**25. (Currently Amended)** A substrate treating apparatus for removing film from a substrate by supplying a treating solution thereto, comprising:

a support means including a chuck rotatable by a motor for supporting and spinning said substrate in a horizontal plane;

a treating solution supply means having including a nozzle for supplying said treating solution having ozone dissolved therein to an upper surface of said substrate;

an ultraviolet emitting means including UV lamps and a reflector for emitting ultraviolet light to said substrate, said ultraviolet emitting means emitting ultraviolet light to said substrate from an irradiating position above said support means; and

wherein, during a film removing process in which said treating solution is supplied from said treating solution supply means to said substrate supported and spun by said support means, said ultraviolet emitting means emits a controller for rotating said support means supporting said substrate, supplying said treating solution from said nozzle of said treating solution supply means to said substrate supported and spun, and, during this film removing process, supplying power to said UV lamps to emit ultraviolet light to said treating solution supplied to said substrate and forming a puddle on an upper surface of said substrate.

**26. (Previously Presented)** An apparatus as defined in claim 25, wherein the ultraviolet light has a wavelength in a range of 242.4 to 300nm.

**27. (Previously Presented)** An apparatus as defined in claim 25, including base adding means for adding a base to the treating solution.

**28. (Previously Presented)** An apparatus as defined in claim 26, including base adding means for adding a base to the treating solution.

**29. - 32. (Canceled)**

33. (New) A substrate treating apparatus, comprising:  
a support rotatable by a motor for supporting and spinning a substrate;  
a cleaning solution supply having a nozzle for supplying a cleaning solution having ozone dissolved therein to an upper surface of said substrate;  
an ultraviolet emitter that emits ultraviolet light onto said substrate from an irradiating position above said support; and  
a controller that controls rotation of the support controls the supplying of said cleaning solution from said nozzle of said cleaning solution supply in a manner that forms a puddle on an upper surface of said substrate and, during this cleaning process, controls supplying power to said emitter to emit ultraviolet light to said cleaning solution supplied to said substrate.

34. (New) An apparatus as defined in claim 33, wherein the ultraviolet light has a wavelength in a range of 242.4 to 300nm.

35. (New) An apparatus as defined in claim 33, including an auxiliary supply for adding a base to the cleaning solution.

36. (New) An apparatus as defined in claim 34, including an auxiliary supply for adding a base to the cleaning solution.

37. (New) An apparatus as defined in claim 33, wherein:  
the support includes a chuck rotatable by a motor for supporting and spinning said substrate in a horizontal plane; and  
the ultraviolet emitter includes UV lamps and a reflector for emitting ultraviolet light to said substrate.